

**Notice of References Cited**

Application/Control No.

09/833,268

Applicant(s)/Patent Under  
Reexamination  
LITKE ET AL.

Examiner

Lance W. Sealey

Art Unit

2671

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-6,198,979 B1	03-2001	Konno	700/98
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Eck et al., Multiresolution Analysis of Arbitrary Meshes, 1995, ACM, pp.173-174
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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